



PLEASE STAMP TO ACKNOWLEDGE RECEIPT OF THE FOLLOWING:

In Re Application of: TAKASHI ISHIGAMI

Confirmation No.: 6183

Application No.: 10/732,888

Group Art Unit: 2822

Filed: December 10, 2003

Examiner: R. Potter

For: INTERCONNECTOR LINE OF THIN FILM, SPUTTER TARGET FOR FORMING THE WIRING FILM AND ELECTRONIC COMPONENT USING THE SAME

1. INFORMATION DISCLOSURE STATEMENT (w/ Form PTO/SB/08 and copies of Official Action issued by the JPO on 1/20/09, English-language Summary thereof, and foreign documents listed on the Form); and
2. Check in the amount of \$180.00.

Dated: April 9, 2009

Docket No.: 04173.0362-01000

RVB/aln - Mail Drop 834



(Due Date: 4/20/09)

Dkt 4-10-09

W. Stewart